

--One noteworthy point in the first aspect of the present invention is that the ratio $d(0.1E_c)/d(1.2E_c)$ is at least 0.43. When the piezoelectric device generates displacement, there exist a piezoelectric displacement component that immediately starts displacement upon application of a voltage and a 90° rotation component that starts displacement with a delay after the application of the voltage, and they together constitute the overall displacement.--

Please replace the paragraph beginning at page 6, line 4 with the following rewritten paragraph:

--It is noteworthy in the fifth aspect that displacement increases with the rise of the temperature within the specific temperature range described above.--

Please replace the paragraph beginning at page 7, line 11 with the following rewritten paragraph:

--It is noteworthy in this seventh aspect that the piezoelectric device has a dielectric loss of 8% or below determined from a P-E hysteresis. In a graph in which an electric field intensity E is plotted on the abscissa and a charge P , on the ordinate, the P-E hysteresis can be obtained by plotting the trajectory of the value of the charge P when the field intensity is increased up to 1.5 kV/mm and is then lowered (see later-appearing embodiments).--

Please replace the paragraph beginning at page 8, line 17 with the following rewritten paragraph:

--It is noteworthy, in the ninth aspect of the present invention, that the piezoelectric device is built and accommodated in the cylindrical accommodation space, and its sectional shape is an octagon or a polygon with a larger number of sides than the octagon.--

Please replace the paragraph beginning at page 9, line 14 with the following rewritten paragraph:

--According to the tenth aspect of the present invention, there is provided a piezoelectric device for an injector, built in an injector and generating a driving force of the injector, characterized in that the piezoelectric device is fabricated by alternately laminating a plurality of piezoelectric layers expanding and contracting in proportion to an applied voltage and a plurality of internal electrode layers for supplying the applied voltage, at least a part, or the whole, of the sectional shape crossing at right angles the laminating direction is arcuate, and the piezoelectric device is accommodated in a cylindrical accommodation space.--

Please replace the paragraph beginning at page 9, line 27 with the following rewritten paragraph:

--It is noteworthy in the tenth aspect of the present invention that the piezoelectric device is built and accommodated in the cylindrical accommodation space, and at least a part, or the whole, of its sectional shape is arcuate. More concretely, when the sectional shape is a polygon, its corners are

rounded to arcs, or a part of the circle is cut into a barrel shape, for example. The radius of curvature of the arcuate shape is preferably close to the radius of curvature of the inner peripheral surface of the cylindrical accommodation space.--

Please replace the paragraph beginning at page 10, line 22 with the following rewritten paragraph:

--According to the eleventh aspect of the present invention, a proximity ratio expressed by $(B/A) \times 100 (\%)$, where A is the total length of a circumscribed circle of the piezoelectric device and B is the sum of the length of the circumferential portions having a distance of 0.2 mm or below between the circumscribed circle and the piezoelectric device, is preferably larger than 17%. Consequently, heat radiation performance of the piezoelectric device can be further improved, and durability can be improved, too. More preferably, according to the twelfth aspect, the proximity ratio described above is 32% or more, and heat radiation performance can be further improved.--

Please replace the paragraph beginning at page 10, line 36 with the following rewritten paragraph:

--According to the thirteenth aspect of the present invention, at least two side surface portions having a width of 2.5 mm or more are disposed on the side surface parallel to the laminating direction. In this case, the space defined between the side surface flat portions and the inner surface of the cylindrical

accommodation space can be effectively utilized, and side surface electrodes for taking out electrodes can be disposed in the piezoelectric device.

Incidentally, disposition of the side electrodes becomes difficult when the width of the side surface flat portion is less than 2.5 mm.--

Please replace the paragraph beginning at page 11, line 11 with the following rewritten paragraph:

--According to the fourteenth aspect of the present invention, an insulating film having a thickness of 0.002 to 0.5 mm is preferably formed on at least the side surface of the piezoelectric device in a direction parallel to the laminating direction. In this way, electric insulation can be secured between the piezoelectric device and the injector accommodating the former, and stable control of the piezoelectric device can be obtained. When the thickness of the insulating film is less than 0.002 mm, sufficient insulation performance cannot be obtained in some cases. When the film thickness exceeds 0.5 mm, on the other hand, heat radiation performance of the piezoelectric device drops.--

Please replace the paragraph beginning at page 11, line 25 with the following rewritten paragraph:

--According to the fifteenth aspect of the present invention, a value $R2 - R1$, where $R1$ is a maximum outer diameter of the piezoelectric device inclusive of the insulating member and $R2$ is an inner diameter of the cylindrical accommodation space, is preferably 0.5 mm or below.

Consequently, heat transfer from the piezoelectric device to the cylindrical accommodation space can be further improved.--

Please replace the paragraph beginning at page 11, line 33 with the following rewritten paragraph:

--According to the sixteenth aspect of the present invention, the insulating film is preferably made of any of a silicone resin, a polyimide resin, an epoxy resin and a fluorocarbon resin. When any of these resins is used, excellent heat resistance capable of withstanding a temperature of 150°C or above, for example, can be obtained in addition to a reliable insulating performance.--

Please replace the paragraph beginning at page 12, line 4 with the following rewritten paragraph:

--According to the seventeenth aspect of the present invention, electrode take-out portions electrically connected to the inner electrode layers are preferably disposed on a distal end face and a rear end face of the piezoelectric device in the laminating direction. In this case, the electrode take-out portions need not be disposed on the side surface of the piezoelectric device in a direction crossing at right angles in the laminating direction, and the structure can be further simplified and rendered compact.--

Please replace the paragraph beginning at page 12, line 14 with the following rewritten paragraph:

--According to the eighteenth aspect of the present invention, either one of the distal end face and the rear end face of the piezoelectric device in the laminating direction is preferably equipped with two electrode take-out portions electrically connected to the inner electrode layers. In this case, electric connection with the piezoelectric device can be established on only one of the end faces. Therefore, not only the structure of the piezoelectric device but also the structure of the arrangement to the injector can be simplified.--

Please replace the paragraph beginning at page 12, line 25 with the following rewritten paragraph:

--According to the nineteenth aspect of the present invention, at least one of the electrode take-out portions is preferably connected electrically to at least one of the inner electrode layers through a through-hole formed in the piezoelectric layers. In this case, the arrangement structure of the electrode take-out portions can be simplified.--

Please replace the paragraph beginning at page 12, line 32 with the following rewritten paragraph:

--According to the twentieth aspect of the present invention, at least one of the electrode take-out portions can take the structure in which it is